

**REMARKS**

In response to Examiner's comments in item 3 of the Office Action, "said nozzle" in line 2 has been amended to read "said nozzles", and "sacrificial layers" in line 3 has been amended to read "sacrificial layer". Applicant thanks Examiner for pointing out there informalities.

A Terminal Disclaimer is also attached to overcome double patenting objection.

Turning to the claim rejections, Applicant respectfully disagrees with Examiner's interpretation of the construction of the Chwalek et al. There is no disclosure in anything other than a very general sense of the manufacturing technique used to construct the nozzle in Chwalek et al. Examiner suggests that Chwalek et al disclose s rim (54) formed by deposition of a rim material layer (column 4, lines 35-38) over a sacrificial layer (50). With respect, no such construction is explicitly disclosed. The "sacrificial layer" referred to by Examiner is actually described at column 4 lines 35-38 as a "heater 50". There is no disclosure of this heater 50 being a sacrificial layer as suggested by Examiner.

Examiner to column 4, lines 35 to 38 to support these conclusions. However, that section of the specification is concerned with construction and etching of the ink delivery channel 40, and doesn't even mention the heater 50 or nozzle rim 54. At best this section discloses formation of the nozzle bore 46, but this is formed in the silicon substrate 42, and does not form part of the nozzle rim.

For all these reasons, it is respectfully submitted that there is no disclosure in Chwalek et al of the features defined in claim 130 of the present invention, and that claim 133 is therefore allowable.

Also, Examiner suggests that the features of claim 133 are disclosed in Chwalek, again with reference to column 4, lines 35 to 37. We reiterate that this section is entirely unconcerned with formation of a nozzle rim which is designated 54 in Chwalek et al), and

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only relates to the formation of the ink channel 40 and nozzle bore 46 in the silicon substrate 42. It is therefore respectfully submitted that claim 133 is also allowable over Chwalek.

Favourable reconsideration of the present application is respectfully requested.

Very respectfully,

Applicant:



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**VERSION WITH MARKINGS TO SHOW CHANGES MADE****In the claims**

**Claim 130 has been amended as follows:**

130. (Twice Amended) An inkjet printhead having a series of nozzles for the ejection of ink wherein each of said nozzles has a rim formed by the deposition of a rim material layer over a sacrificial layer[s] and a subsequent planar removal of at least said rim material layer so as to form said nozzle rim.

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